

Amendments to the Specification:

Please replace the paragraph beginning at p. 22, line 17, with the following rewritten paragraph:

[0055] The surface acoustic wave element 3 for reference also consists of, similar to the surface acoustic wave element 2 for detecting pressure, an IDT ~~6a~~ 3a formed on the surface of the sensor substrate 1 and reflectors ~~6b~~ 3b formed on both sides in a surface acoustic wave propagation direction of the IDT ~~6a~~ 3a. The method of manufacturing is the same as that for the surface acoustic wave element 2 for detecting pressure.

Please replace the paragraph beginning at p. 22, line 24, with the following rewritten paragraph:

[0056] A junction 8 is annularly formed on the surface of the sensor substrate 1 so as to surround the surface acoustic wave element 2 for detecting pressure and the surface acoustic wave element 3 for reference. The junction 8 can be formed from the same material by the same method as those for the IDTs 2a and ~~6a~~ 3a and the reflectors 2b and ~~6b~~ 3b. The surface thereof is subjected to Ni plating or Au plating. For improvement adhesion strength, preferably, the film thickness of the junction 8 is formed thick.